



AF 2/1w

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re application of : Confirmation No. 7745
Shoriki NARITA et al. : Docket No. 2003_1226
Serial No. 10/651,103 : Group Art Unit 2891
Filed August 29, 2003 : Examiner Igwe U. Anya

Corres. and Mail
BOX AF

BUMP FORMING APPARATUS FOR CHARGE
APPEARANCE SEMICONDUCTOR SUBSTRATE,
CHARGE REMOVAL METHOD FOR CHARGE
APPEARANCE SEMICONDUCTOR SUBSTRATE,
CHARGE REMOVING UNIT FOR CHARGE
APPEARANCE SEMICONDUCTOR SUBSTRATE,
AND CHARGE APPEARANCE SEMICONDUCTOR SUBSTRATE

THE COMMISSIONER IS AUTHORIZED
TO CHARGE ANY DEFICIENCY IN THE
FEES FOR THIS PAPER TO DEPOSIT
ACCOUNT NO. 23-0975

AMENDMENT AFTER FINAL

Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

RESPONSE UNDER 37. CFR 1.116
EXPEDITED PROCEDURE
EXAMINING GROUP 2891

Sir:

Responsive to the Office Action dated March 29, 2005, please amend the
above-identified application as follows.